

<b>Notice of References Cited</b>		Application/Control No.	Applicant(s)/Patent Under Reexamination	
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Examiner		Art Unit		Page 1 of 1
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*	C	US-5,867,302	02-1999	Fleming, James G.	359/291
*	D	US-6,384,952 B1	05-2002	Clark et al.	359/224.1
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	X	Bifano et al., "Surface Micromachined Deformable Mirrors", Conference on Emerging Technologies and Factory Automation (1996), Vol. 2, pp 393-399.

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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